

ABSTRACT

METHOD OF ADJUSTING SUBSTRATE TRANSFER
POSITION, SUBSTRATE TRANSFER METHOD, AND SUBSTRATE
5 PROCESSING SYSTEM

A method of adjusting a substrate transfer position is provided in a substrate processing system including: a batch processing section; a
10 single-substrate processing section; and a substrate standby section configured to cause a substrate to be transferred from the batch processing section to the single-substrate processing section to wait. The substrate standby section includes: a delivery
15 table; and a first transfer robot including a first holding section. The single-substrate processing section includes a second transfer robot including a second holding section. The method includes:
20 acquiring, by the second holding section, the substrate from the delivery table; detecting a shift amount of the substrate with respect to a reference position while the second holding section holds the substrate acquired from the delivery table; and
25 correcting a horizontal position when the first holding section mounts the substrate on the delivery table, based on the detected shift amount.

FIG. 1